

Yuelin Wang

List of Publications by Year in descending order

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11
papers

572
citations

1307594

7
h-index

1281871

11
g-index

11
all docs

11
docs citations

11
times ranked

890
citing authors

#	ARTICLE	IF	CITATIONS
1	Silicon-Nanowire-Based CMOS-Compatible Field-Effect Transistor Nanosensors for Ultrasensitive Electrical Detection of Nucleic Acids. <i>Nano Letters</i> , 2011, 11, 3974-3978.	9.1	257
2	Enhanced Sensing of Nucleic Acids with Silicon Nanowire Field Effect Transistor Biosensors. <i>Nano Letters</i> , 2012, 12, 5262-5268.	9.1	189
3	Wafer-level and highly controllable fabricated silicon nanowire transistor arrays on (111) silicon-on-insulator (SOI) wafers for highly sensitive detection in liquid and gaseous environments. <i>Nano Research</i> , 2018, 11, 1520-1529.	10.4	32
4	Top-Down Fabricated Silicon Nanowire-Based Field-Effect Transistor Device on a (111) Silicon Wafer. <i>Small</i> , 2013, 9, 525-530.	10.0	29
5	Design, fabrication, and characterization of a high-performance CMOS-compatible thermopile infrared detector with self-test function. <i>Journal of Micromechanics and Microengineering</i> , 2018, 28, 125017.	2.6	18
6	SiC emitters for nanoscale vacuum electronics: A systematic study of cathode-anode gap by focused ion beam etching. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2017, 35, .	1.2	13
7	MEMS thermal gas flow sensor with self-test function. <i>Journal of Micromechanics and Microengineering</i> , 2019, 29, 125009.	2.6	13
8	Gold nanoparticle modified silicon nanowire array based sensor for low-cost, high sensitivity and selectivity detection of mercury ions. <i>Materials Research Express</i> , 2020, 7, 035017.	1.6	8
9	Simultaneously controlling heat conduction and infrared absorption with a textured dielectric film to enhance the performance of thermopiles. <i>Microsystems and Nanoengineering</i> , 2021, 7, 36.	7.0	6
10	Size-dependent mechanical behavior of a-silicon carbide nanowires under <i>in-situ</i> transmission electron microscopy tensile tests. <i>Materials Research Express</i> , 2019, 6, 045009.	1.6	4
11	Novel fabrication for vertically stacked inverted triangular and diamond-shaped silicon nanowires on (100) single crystal silicon wafer. <i>Journal of Micromechanics and Microengineering</i> , 2020, 30, 015003.	2.6	3